

**IN THE UNITED STATES AND TRADEMARK OFFICE**

In re application of: **Mariner et al.**  
U.S. Serial No.: \_\_\_\_\_  
Filed: Concurrently Herewith

Examiner: \_\_\_\_\_  
Group Art Unit: \_\_\_\_\_  
Docket No.: 131067-2 60QZ

**FOR: WAFER HANDLING APPARATUS AND METHOD OF MANUFACTURING THEREOF**

Mail Stop Patent Application  
Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

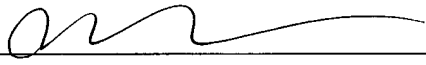
CITATION UNDER 37 CFR 1.97

Sir:

Attached is a form PTO-1449 listing document(s) which may be considered material to the examination of the above identified application. The reasons for the relevancy are given in the Specification. A copy of each document is also enclosed for non-US patent documents. It is requested that these documents be considered by the Examiner and officially made of record in accordance with the provisions of 37 CFR 1.97 and Section 609 of the MPEP.

Respectfully submitted,


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January 16, 2004

  
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**CERTIFICATE OF MAILING**

I hereby certify that this correspondence is being deposited into the United States Postal Service as Express Mail in an envelope addressed to: Mail Stop Patent Application, Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450, on this 16<sup>th</sup> day of January 2004. EXPRESS MAIL NO: EL 851487371

  
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Hanh T. Pham

Form PTO-1449 (Reproduced)				Docket Number (Optional) 131067-2 QZ		Application Number Not assigned yet	
<b>INFORMATION DISCLOSURE CITATION IN AN APPLICATION</b> <i>(Use several sheets if necessary)</i>				Applicant <b>GENERAL ELECTRIC COMPANY</b>			
				Filing Date 16JAN2004		Group Art Unit	
<b>U. S. PATENT DOCUMENTS</b>							
EXAMINER INITIAL	DOCUMENT NUMBER	DATE	NAME	CLASS	SUBCLASS	FILING DATE IF APPROPRIATE	
	6214121	Apr. 10, 2001	Cho et al.	118	724		
	2002/0051848	May 2, 2002	Chou	427	376.6		
	6023405	Feb. 8, 2000	Shamouilian et al.	361	234		
	2003/0080109	May 1, 2003	Choi et al.	219	444.1		
	5231690	Jul. 27, 1993	Soma et al.	392	416		
	5702764	Dec. 30, 1997	Kimura	427	248.1		
	6066836	May 23, 1000	Chen et al.	219	390		
	20030164369	Sep. 4, 2003	Goetz	219	543		
	5343022	Aug. 30, 1994	Gilbert et al.	219	552		
	6507006	Jan. 14, 2003	Hiramatsu et al.	219	444.1		
	5280156	Jan. 18, 1994	Niori et al.	219	385		
	6410172	Jun. 25, 2002	Gilbert et al.	428	698		
	6066836	May 23, 2000	Chen et al.	219	390		
<b>FOREIGN PATENT DOCUMENTS</b>							
	DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUB- CLASS	TRANSLATION	
						YES	NO
<b>OTHER DOCUMENTS</b> <i>(Including Author, Title, Date, Pertinent Pages, Etc.)</i>							
EXAMINER				DATE CONSIDERED			
EXAMINER: Initial if citation considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.							